

INFORMATION DISCLOSURE STATEMENT

Applicant	:	Taku Hirayama et al.
App. No	:	10/590,046
Filed	:	June 15, 2007
For	:	BASE MATERIAL FOR PATTERN- FORMING MATERIAL, POSITIVE RESIST COMPOSITION AND METHOD OF RESIST PATTERN FORMATION
Examiner	:	Connie P. Johnson
Art Unit	:	1795

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing two (2) references to be considered by the Examiner. Also enclosed are two (2) foreign patent references and/or non-patent literature as listed on the Information Disclosure Statement.

This Information Disclosure Statement is being filed before the mailing date of a final action and before the mailing date of a Notice of Allowance.

CERTIFICATION UNDER 37 C.F.R. § 1.97(e)(1)

I hereby certify that each item of information contained in this Statement was first cited in any communication from a foreign Patent Office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement.

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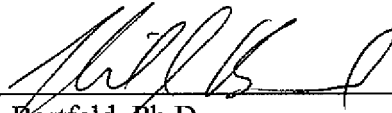
Docket No. SHIGA7.055APC
Customer No. 20,995

Thus, no fee is required as set forth in 37 C.F.R. § 1.97(c), however, the Commissioner is hereby authorized to charge any additional fees which may be required or to credit any overpayment to Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 10/23/08

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